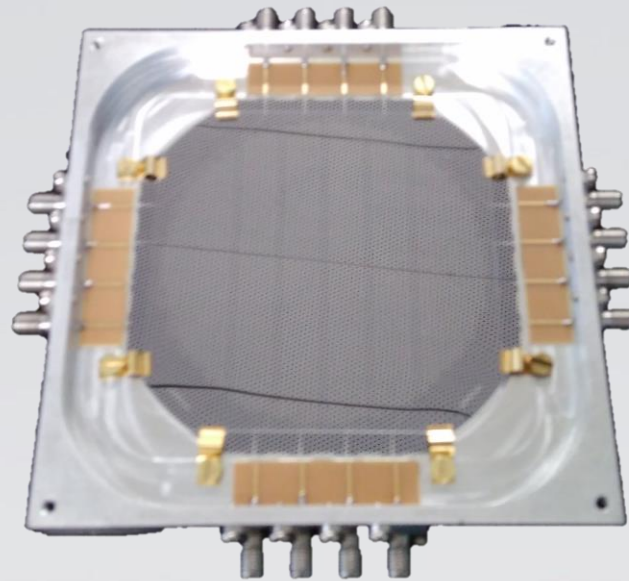




# KIDs arrays for NIKA2



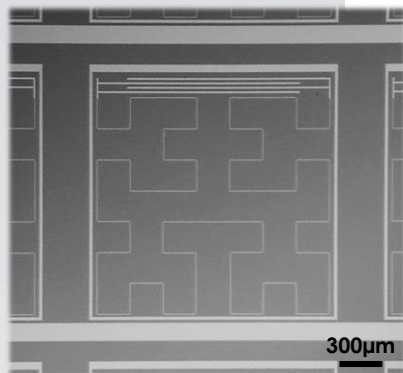
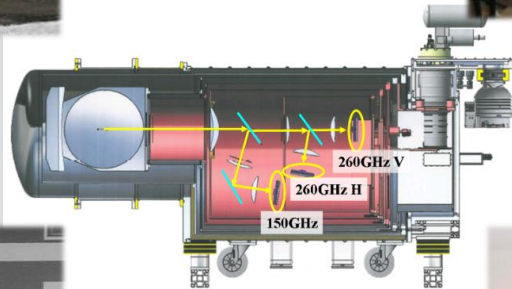
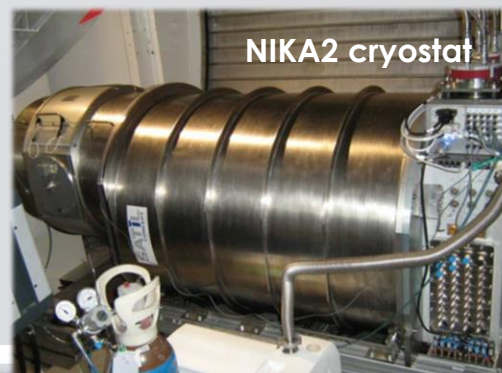
Grenoble – June 2019 – NIKA2 conference

# Context

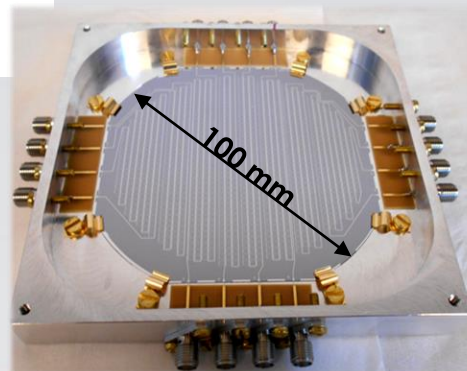
Telescope at Pico Veleta (Spain)



The NIKA2 instrument installed in the cabin



2mm array : 1 pixel



NIKA2 array (1200 pixels)

## Context

### I/ Microtechnology process

- standard
- Microstrip

### II/ "Generation 1" Arrays

- 1mm
- 2mm

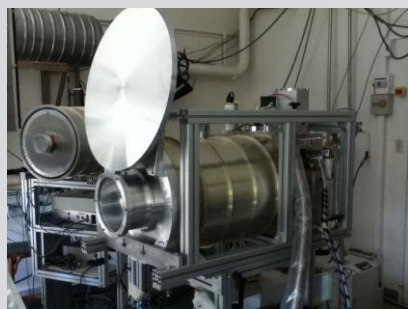
### III/ "Generation 2" Arrays

- 1mm
- 2mm

### IV/ Last developments for NIKA's arrays

- 1mm thin substrate
- perspectives

### NIKA1 technology roots



- CPW feedline



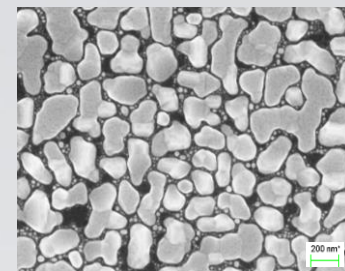
The ground plane is also the electromagnetic shield around each pixel.

The illumination is by the back side. A mirror is positioned on the top side to realize a  $\lambda/4$  cavity.

- Aluminum thin layer

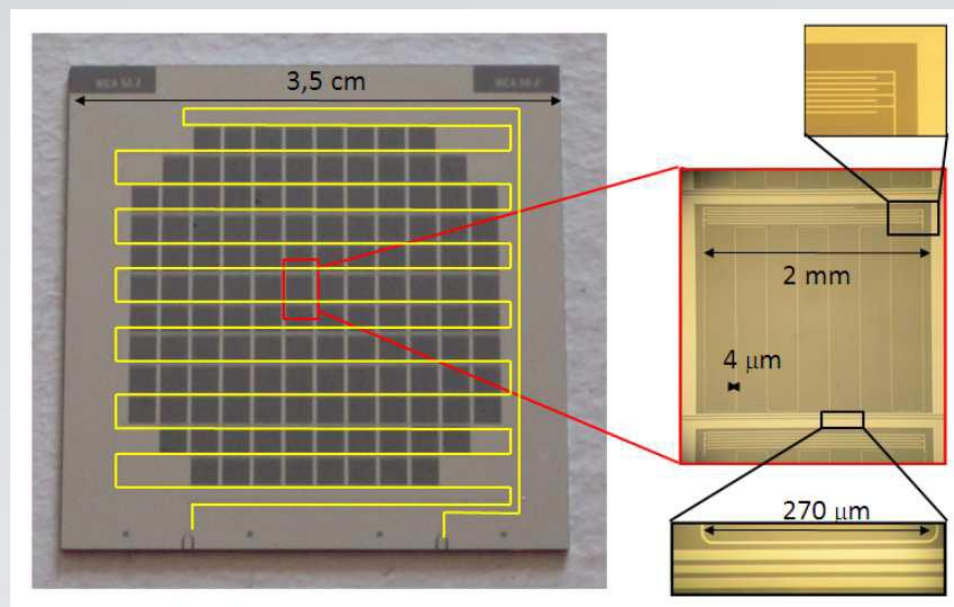
Superconducting gap:  
 $\sim 110$  GHz

Lk  $\sim 2$  pH /  $\square$



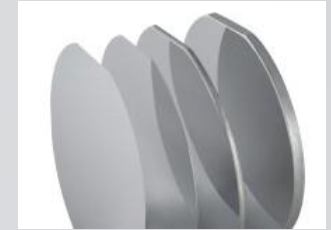
20 nm thickness

- 2 geometry patterns for 2 bands:  
1mm  $\rightarrow$  120 – 180 GHz  
2mm  $\rightarrow$  220 – 280 GHz



# Microtechnology Process

## Standard technological Process : Clean Room



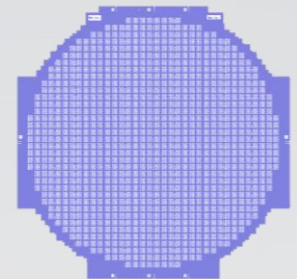
On a 4 inch silicon mono crystalline and high purity ( $> 1000\Omega\cdot\text{cm}$ ) wafer, a thin layer (18nm) of aluminium is coated by electron beam evaporator (under a residual vacuum  $5\cdot 10^8$  mbar)



Print patterns via optical lithography ( $\lambda = 365\text{nm}$ ) through a dedicated mask



The metal is etched by a chemical (phosphoric acid) solution through resist apertures.



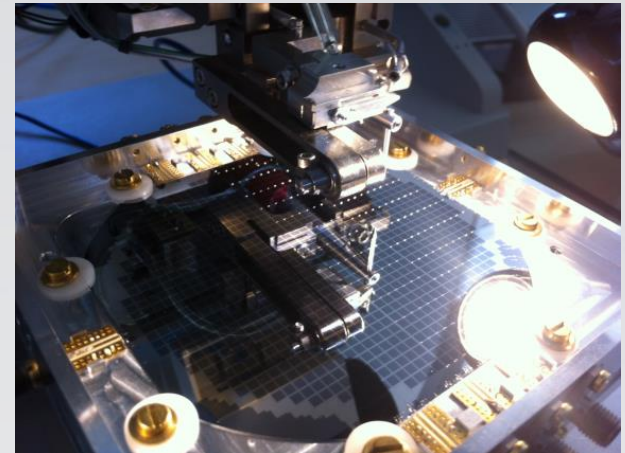
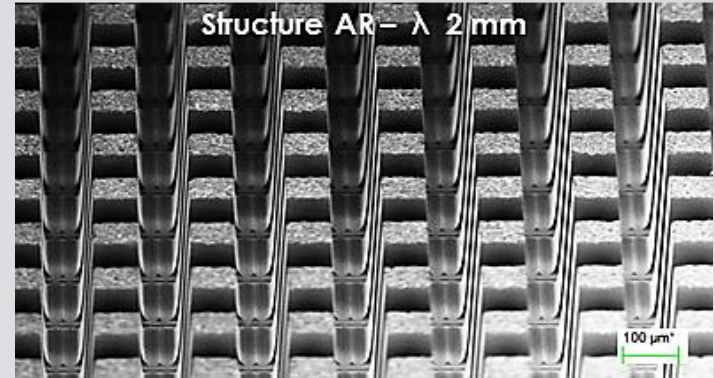
**Hard points:** The homogeneity of the aluminum layer, have a full 4 inch surface without major defects (dust, bubbles)

## Standard technological Process: Packaging

Dicing the edges of the array, and structure the backside of array to add a function of optical adaptation layer (AR).

The AR strategy is to reduce the silicon density by grooves to obtain an effective index  
 $n_{\text{void}} = 1 < n_{\text{adapt}} \sim 2 < n_{\text{Si}} \sim 3.4$

After mounting in a dedicated holder, connect the feedlines and improve the equipotentiality of the ground plan by sticking small bridges above the signal line (25 $\mu\text{m}$  diameter wires).



# “Generation 1” Arrays

## 2mm arrays, tested in NIKA2 @ Grenoble

CPW feedline, Al 18nm, Si 300 $\mu$ m,  
1020 pixels, pitch 2,1mm

Spectral band  $\sim$  130 – 170 GHz  
**Without AR**

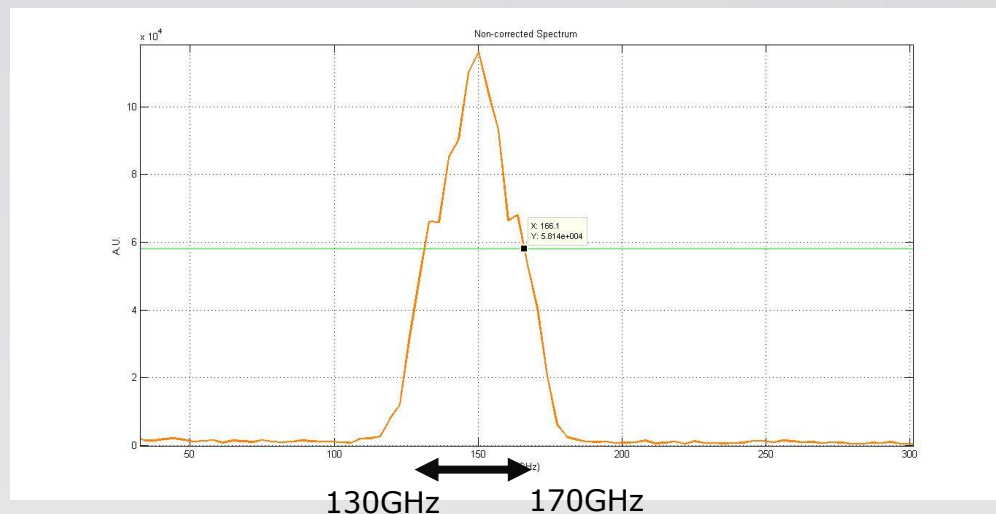
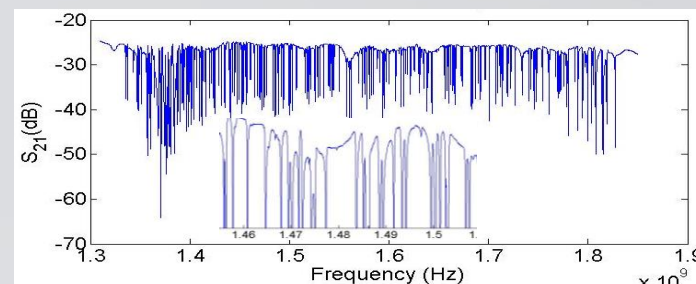
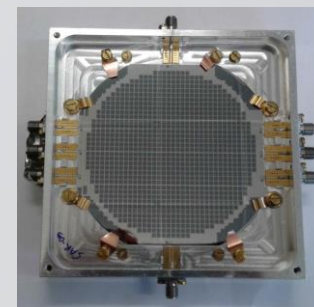
90% good pixels

$Q_i \sim 30$  k (sky 50 K)

$Q_c \sim 20$  k

Optical resp (50 vs 300 K)  
 $= 200$  kHz

Noise  $\sim 2$  Hz/Hz<sup>0.5</sup>



# “Generation 1” Arrays

## 2mm arrays, tested in NIKA2 @ Grenoble

CPW feedline, Al 18nm, Si 525 $\mu$ m,  
1020 pixels, pitch 2,1mm

Spectral band  $\sim$  125 – 175 GHz  
**With AR** (250 $\mu$ m)

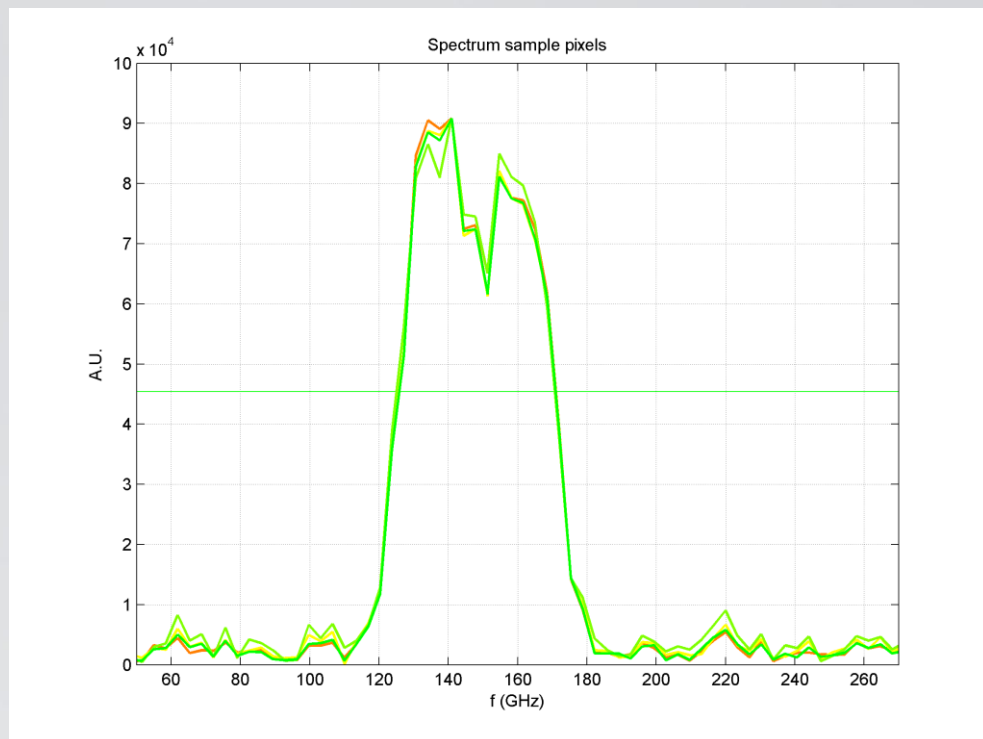
90% good pixels

$Q_i \sim$  30 k (sky 50 K)

$Q_c \sim$  12 k

Optical resp (50 vs 300 K)  
= 200 kHz

Noise  $\sim$  2 Hz/Hz<sup>0.5</sup>



The width and the area of the effective spectral band is increased by AR



# “Generation 1” Arrays

## 1mm arrays, tested in NIKA2 @ Grenoble

CPW feedline, Al 20nm,  
Si 180 $\mu$ m, 1200pix, pitch 1,6mm

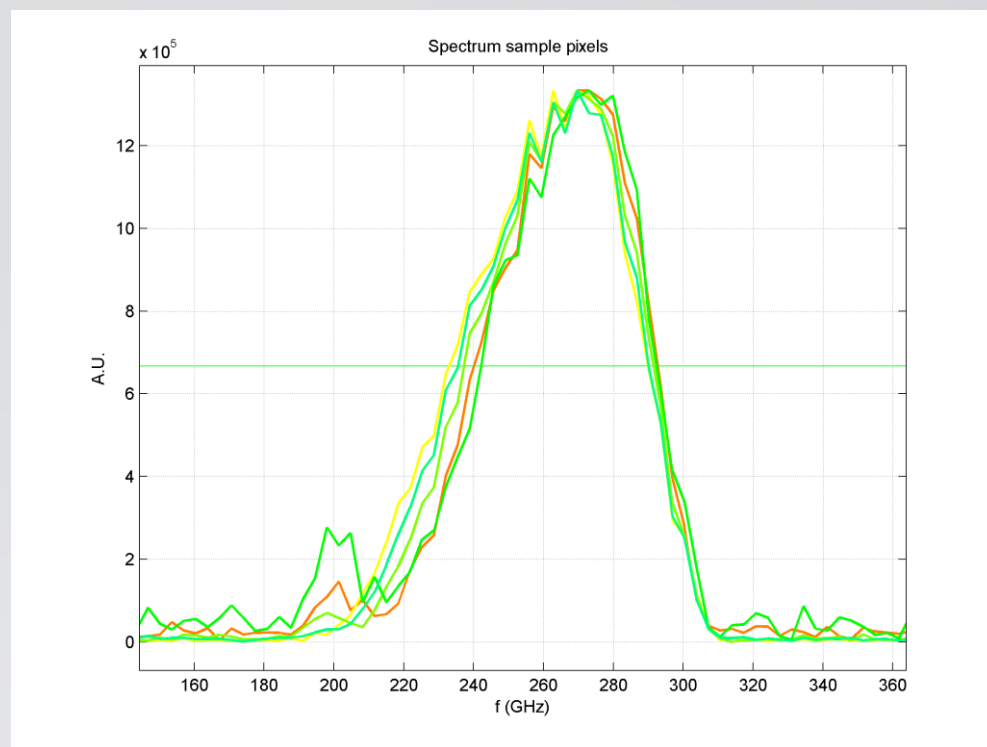
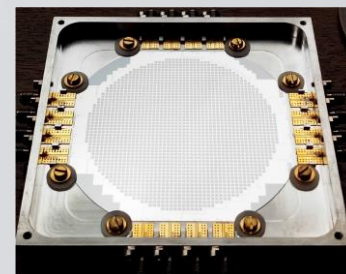
Spectral band  $\sim$  240 – 290 GHz  
**Without AR**

$Q_i \sim 14$  k (sky 50 K)

$Q_c \sim 20$  k

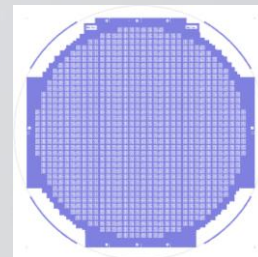
Optical resp (50 vs 300 K)  
= 600 kHz

Noise  $\sim 4$  Hz/Hz<sup>0.5</sup>



# “Generation 1” Arrays

1mm arrays, tested in NIKA2 @ Grenoble



CPW feedline, Al 25nm,  
Si 350 $\mu$ m, 1200pix, pitch 1,6mm

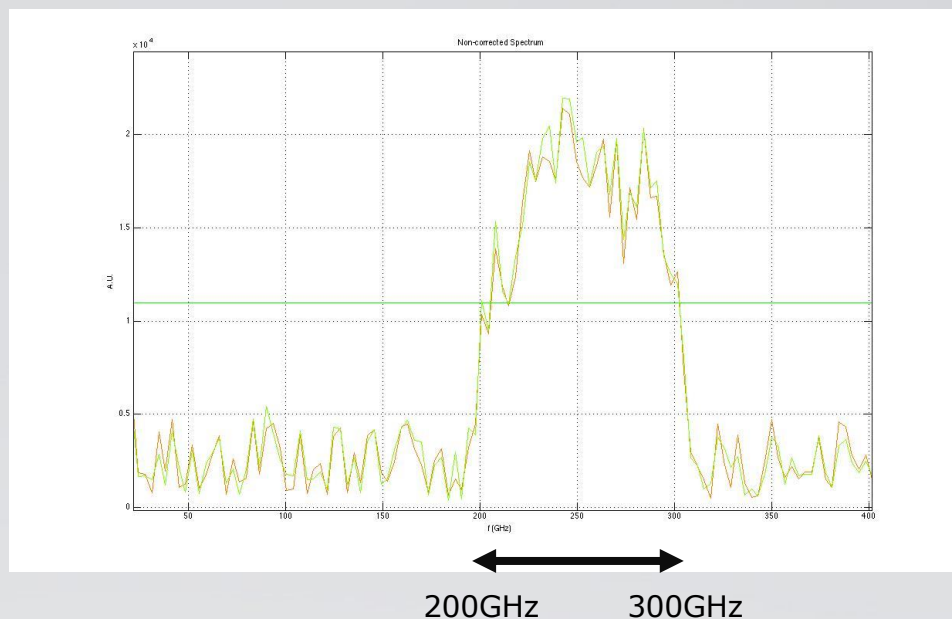
Spectral band  $\sim$  200 – 300 GHz  
**With AR (150 $\mu$ m)**

$Q_i \sim 16$  k (sky 50 K)

$Q_c \sim 25$  k

Optical resp (50 vs 300 K)  
= 500 kHz

Noise  $\sim 5$  Hz/Hz<sup>0.5</sup>



The width and the area of the effective spectral band is increased by AR

In this first period (12 months) around 40 arrays has been fabricated by Grégoire Coiffard (IRAM), Alessandro Monfardini and Johannes Goupy (Neel Institute).

# “Generation 2” Arrays

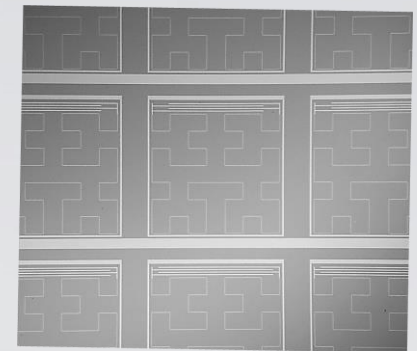
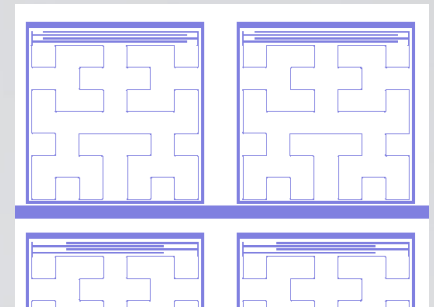
## Improve the technology

Change the feedline strategy. Using Microstrip :  
Thanks to the backside ground plane, no need for bridges.

We have modified the design to adjust the coupling by adding a “loop” (electromagnetic shield effect) around the pixel.

In this configuration, the illumination is by the top side.  
The thickness of the silicon wafer determines the  $\lambda/4$  cavity above the mirror of aluminum (200nm) layer on the backside.

We have initiated a study to understand the source of resonance shuffling.



# “Generation 2” Arrays

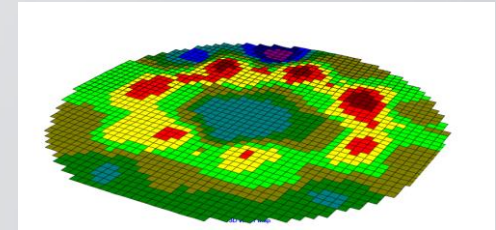
KIDs arrays for NIKA2

## Improve the technology

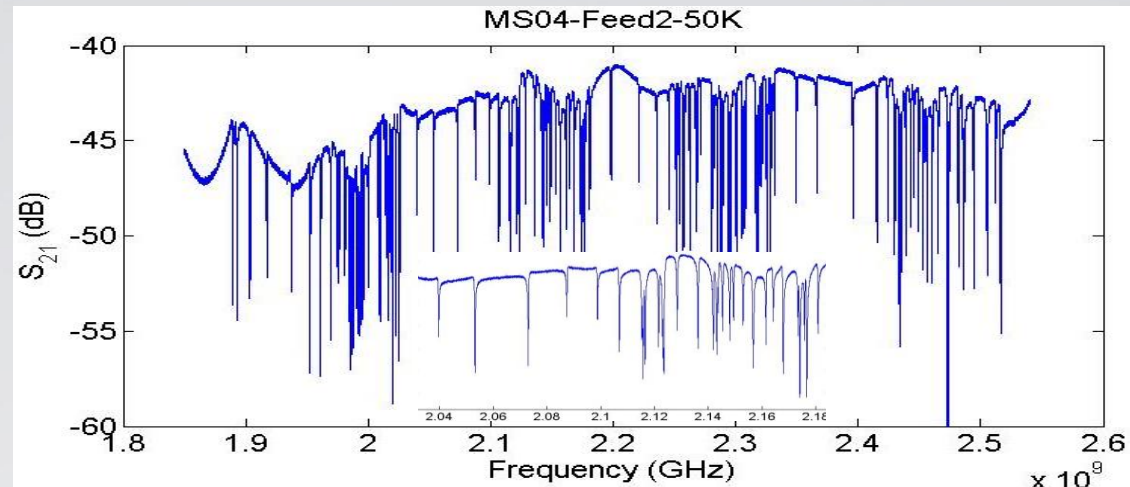
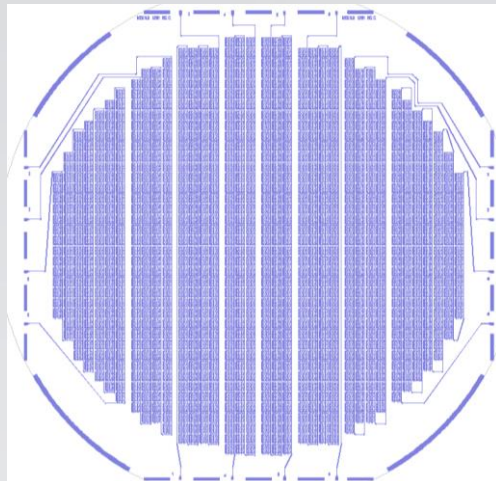
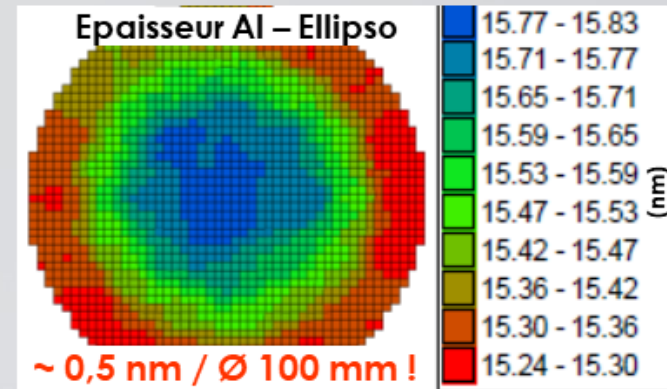
We have initiated a study to understand the source of the resonance shuffling in order to reduce double pixels

The main source of shuffling is mainly due to the aluminum thickness variation across the wafer (center to edge)

The variation is tiny, but it has a huge impact on the kinetic inductance ( $0,5\text{nm} \rightarrow \sim 5\%$ )



Al evap PTA 18 nm  $\pm$  0,5 nm



# “Generation 2” Arrays

KIDs arrays for NIKA2

## 2mm arrays, tested in NIKA1.5 @ Grenoble

MS feedline, Al 18nm,  
Si 156 $\mu$ m, 616pix, pitch 2.8mm

Spectral band  $\sim$  125 – 180 GHz

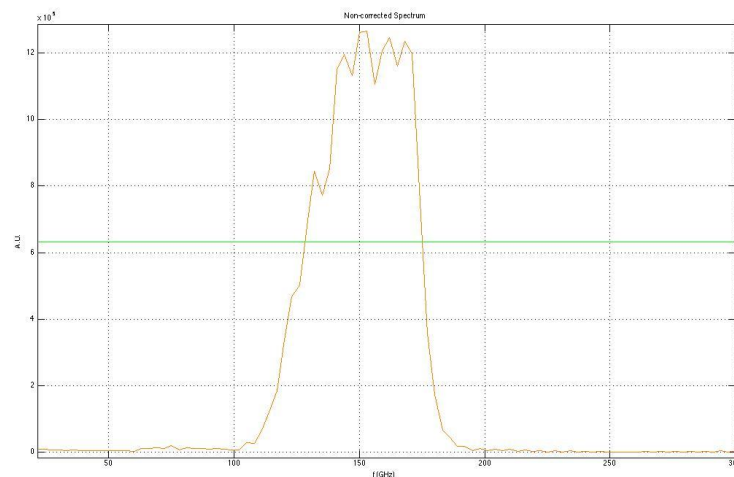
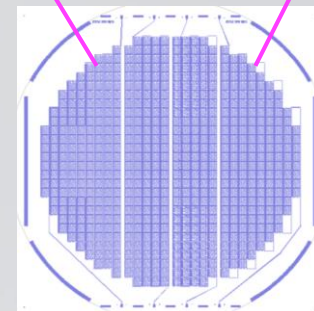
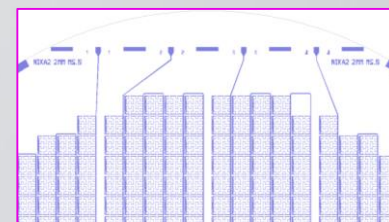
$Q_i \sim 50$  k (sky 50 K)

$Q_c \sim 12$  k

Optical resp (50 vs 300 K)  
= 120 kHz

Noise  $\sim 1$  Hz/Hz<sup>0.5</sup>

Preserve the good spectral band by a  $\lambda/4$  cavity, and decrease the noise  
→ Final array !



125GHz 180GHz

# “Generation 2” Arrays

## 1mm arrays, tested in NIKA1.5 @ Grenoble

MS feedline, Al 20nm,  
Si 240 $\mu$ m, 1140pix, pitch 2.0mm

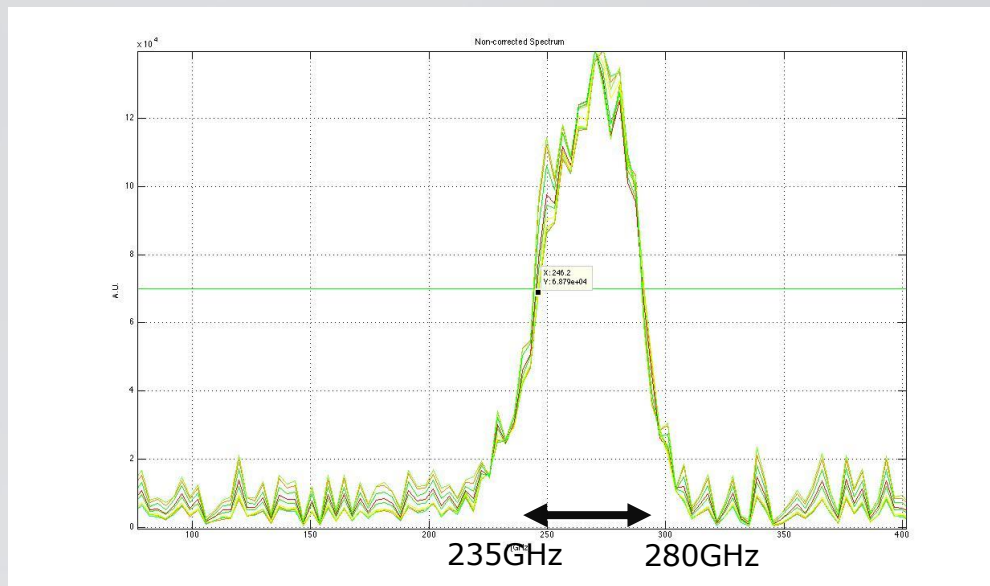
Spectral band  $\sim$  235 – 280 GHz

$Q_i \sim$  18 k (sky 50 K)

$Q_c \sim$  12 k

Optical resp (50 vs 300 K)  
= 500 kHz

Noise  $\sim$  4 Hz/Hz<sup>0.5</sup>

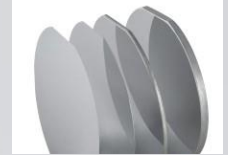


Not the full spectral band due to the  $3\lambda/4$  cavity.  
→ Change technology

# Last developments

## 1 mm arrays with $\lambda/4$ (90 $\mu\text{m}$ ) thickness silicon wafer

The main difficulty is the manipulation of very thin crystalline wafers.  
With a lot of care, we still break 30% of them..



MS feedline, Al 20nm,  
Si 90 $\mu\text{m}$ , 1124pix, pitch 2mm

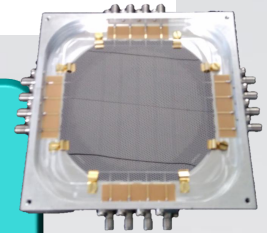
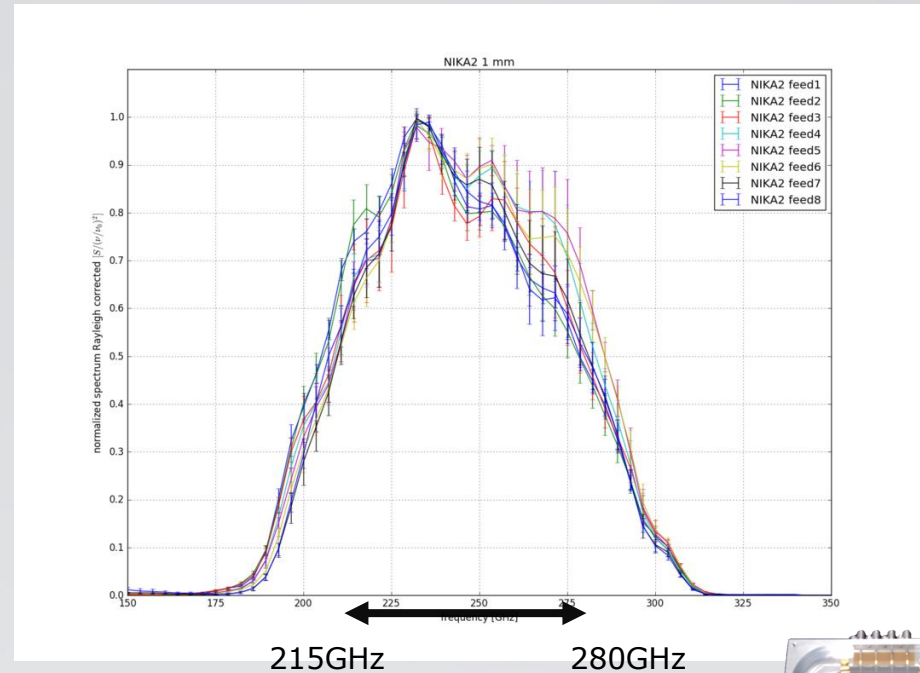
Spectral band  $\sim$  215 – 280 GHz

$Q_i \sim$  18 k (sky 50 K)

$Q_c \sim$  15 k

Optical resp (50 vs 300 K)  
 $=$  350 kHz

Noise  $\sim$  3 Hz/Hz<sup>0.5</sup>



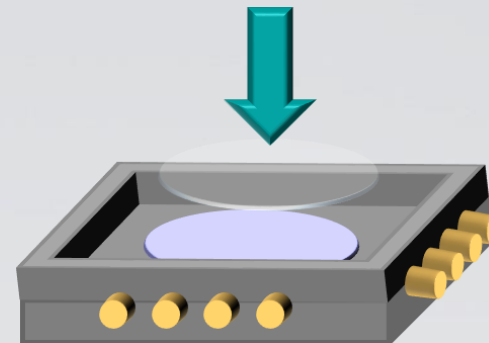
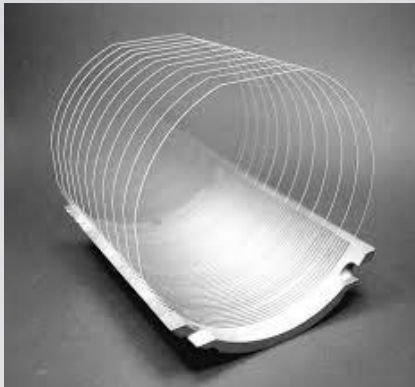
Full spectral band thanks to the  $\lambda/4$  cavity.

→ We have already 3 spare arrays fully tested for 1mm band waiting to be mounted in the instrument at Pico Veleta.

## Perspectives

Another option to increase the absorption of the arrays will be to add an AR layer on top of the MS arrays.

For CONCERTO, we have demonstrated that by covering the top face of arrays with a quartz wafer (ad-hoc thickness), it is possible to make a AR layer without increasing the noise of the detectors.



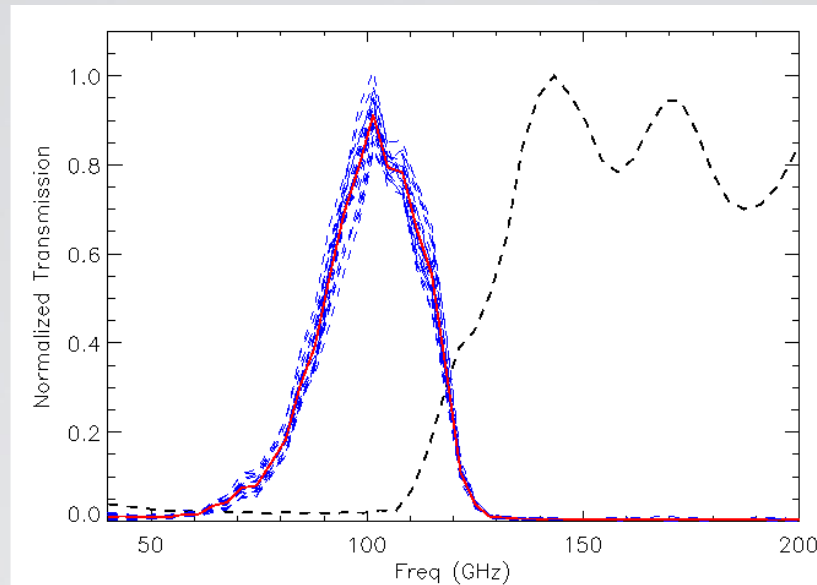
Another way has been developed by **Shibo (IRAM)** to reduce drastically the shuffling of the position of the resonances and recovering the 10% of resonators lost.



## Perspectives

Lower frequency absorption:

If we replace the aluminum layer of the KID by a Titanium (10nm) / Aluminum (25nm) bilayer, the superconducting gap decreased thanks to the superconductors proximity effect. This opens the way to the "3mm" (90GHz) band.



**Thank you !**